

| Ref # | Hits | Search Query | DBs | Default Operator | Plurals | Time Stamp |
|-------|------|-----------------------------------------------------------------------------------------------|----------------------------|------------------|---------|------------------|
| L2 | 38 | (substrate or wafer or disc or disk) and (clean\$3 or scrub\$4) and edge and brush and roller | EPO; JPO; DERWENT; IBM_TDB | OR | ON | 2005/12/27 10:00 |
| L3 | 0 | (substrate or wafer or disc or disk) and (clean\$3 or scrub\$4) and roller and vertical2 | EPO; JPO; DERWENT; IBM_TDB | OR | ON | 2005/12/27 10:01 |
| L4 | 2249 | (substrate or wafer or disc or disk) and (clean\$3 or scrub\$4) and roller | EPO; JPO; DERWENT; IBM_TDB | OR | ON | 2005/12/27 10:01 |
| L5 | 357 | l4 and brush | EPO; JPO; DERWENT; IBM_TDB | OR | ON | 2005/12/27 10:01 |
| L6 | 153 | l5 and (edge or side or peripher\$2) | EPO; JPO; DERWENT; IBM_TDB | OR | ON | 2005/12/27 10:02 |